

INLINE Thin Film Deposition



INGENUITY THAT DRIVES YOUR BUSINESS FORWARD

Dynavac has been designing, manufacturing and supporting thin film deposition systems for over 40 years. Our customers are in a wide range of industries, but they share the same expectation: top-quality performance and consistent results, process after process, year after year.



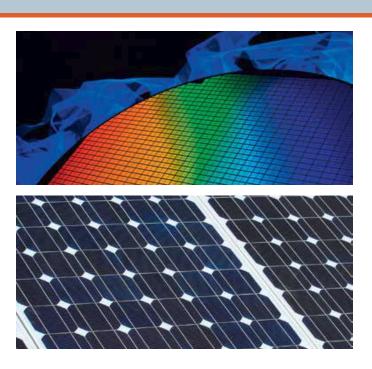
Maximum throughput. Consistent quality. Minimal downtime.

Dynavac's Inline systems offer the highest performance and lowest cost solution for a variety of thin film deposition requirements.

Engineering Expertise That Ensures Your Success

When you partner with Dynavac, you work directly with scientists and engineers with hands-on experience with your application.

- Perform initial process development and produce coatings to provide assurance before your equipment is delivered.
- Design and fabricate custom fixtures to meet your specific application needs.
- Provide flexible control system architecture customizable for your production requirements.





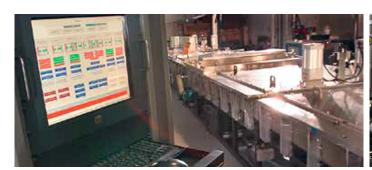
Inline System Features

- Modular vacuum chambers for scalability
- Sputtering, evaporation, or ion-assisted deposition
- Fully automated production
 - Material handling systems
 - Integrated control systems
- Low cost of ownership
- Custom engineered fixtures to handle a wide range substrate types and sizes

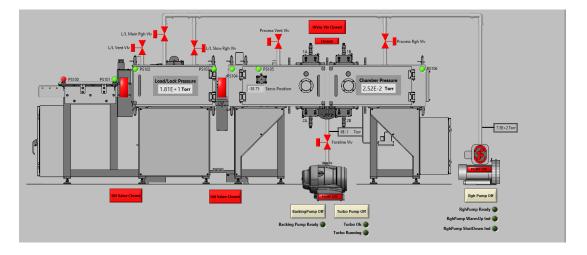
Applications

- Anti-reflection coatings
- Transparent conductive-oxide coatings
- Substrate metalization
- EMI shielding coatings
- Decorative coatings
- Substrate pre-post treatments (Plasma and thermal)









SPECIFICATIONS

Vacuum Chambers	Modular and flexible multi-chamber designHigh-duty chamber isolation valves	
Material Handling	 Tray, pallet or roller based conveyor systems to accommodate a variety of substrate geometries Flat/rigid Flexible Three dimensional Accurate control and sensing to ensure precise positioning throughout system 	
Pumping System	 High vacuum: crypopumps, turbopumps and diffusion pumps Rough: single or multistage mechanical pumps Water vapor pumping systems 	
Process	Substrate Treatment Heat Plasma Cooling	 Deposition methods Magnetron sputtering Electron beam evaporation Ion assisted deposition
System Control	 Fully automated system and process control Supervisory control system with HMI interface Enhanced data logging and trending capabilities Remote login feature Integrated quartz crystal monitoring Residual gas analyzer Plasma emission monitor 	
System Commissioning	 Systems fully assembled and tested prior to shipment Installation, start-up and post-installation support 	

